

AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

1-12 (Canceled).

13. (Currently Amended) A method of cleaning a substrate of a liquid crystal display panel comprising:

~~providing a first cleaning module on a substrate, said substrate having upper and lower surfaces;~~

~~providing a side cleaning module on a side surface of the substrate;~~

~~removing foreign substances on a side surface of the substrate using the side cleaning module; and~~

~~removing foreign substances on the upper and lower surface of the substrate using the cleaning module transferring the substrate;~~

~~cleaning a side surface of the substrate by jetting deionized water onto the side surface of the substrate and by brushing the side surface of the substrate with a brush that extends partially along the side surface of the substrate; and~~

~~cleaning upper and lower surfaces of the substrate.~~

14. (Currently Amended) The method of claim 13, wherein the ~~side cleaning module~~ brush is rotatable.

Claim 15 (Canceled).

16. (Currently Amended) The method of claim 13, wherein the ~~first cleaning module is~~
~~rotatable~~ cleaning upper and lower surfaces of the substrate is performed by rotatable brushes.

Claim 17 (Canceled).

18. (Currently Amended) The method of claim 16, wherein the ~~upper and lower~~ cleaning
brushes are arranged at the upper and lower surfaces of the substrate, respectively.

Claim 19 (Canceled).

20. (Currently Amended) The method of claim 18, wherein the deionized water ~~jet device~~
~~generates~~ is jetted onto the side surface of the substrate with ultrasonic waves.

Claims 21 and 22 (Canceled).

23. (Currently Amended) A method of cleaning a substrate of a liquid crystal display panel
comprising:

transferring the substrate;

~~providing a cleaning module at a substrate, said substrate having upper and lower~~
~~surfaces;~~

~~providing a side cleaning module arranged at a side surface of the substrate;~~

removing foreign substances on a side surface of the substrate using ~~[[the]]~~ a side-cleaning module having a water jet device jetting deionized water onto the side surface of the substrate and including cleaning brushes that extend partially along the side surface of the substrate; and

removing foreign substances on the upper and lower surfaces of the substrate using the cleaning module; ~~and~~

~~cleaning the side surface of the substrate using a water jet device.~~

24. (Original) The method of claim 22, wherein the water jet device causes vibration on the side surface of the substrate.

25. (Original) The method of claim 23, wherein the vibration is generated by ultrasonic waves.

Claims 26 and 27 (Canceled).

28. (New) A method of cleaning a substrate having an upper surface and a lower surface separated by at least two opposing side surfaces, the method comprising:

brushing at least two opposing side surfaces;

cleaning at least one of the upper and lower surfaces; and

spraying water onto the at least two brushed side surfaces.

29. (New) The method of claim 28, further including brushing at least two opposing side surfaces before brushing at least one of the upper and lower surfaces.

30. (New) The method of claim 28, wherein the water includes deionized water.
31. (New) The method of claim 28, further including exposing the at least two brushed side surfaces to ultrasonic energy.
32. (New) The method of claim 28, wherein cleaning at least one of the upper and lower surfaces includes brushing the at least one of the upper and lower surfaces.